

**AMENDMENTS TO THE CLAIMS:**

1. (Original) An electron microscope, comprising:  
a main vacuum chamber housing a stage therein and connected to a vacuum pump;  
a load lock for loading a specimen into said main vacuum chamber;  
a minicolumn non-translatably positioned inside said main chamber; and  
a vacuum pump situated inside the main vacuum chamber and external to and connected  
to the minicolumn.

2. (Cancelled)

3. (Cancelled)

4. (Cancelled)

5. (Cancelled)

6. (Cancelled)

7. (New) An electron microscope comprising:  
a main vacuum chamber connected to a vacuum pump and housing;  
a turntable stage for holding a semiconductor wafer thereon; and  
a plurality of minicolumns;  
wherein imaging of every point on the wafer by the minicolumns is enabled by the  
turntable rotating the wafer.

8. (New) The electron microscope of claim 7, wherein each of the minicolumns  
comprises a plurality of lenses, all of which are electrostatic.

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